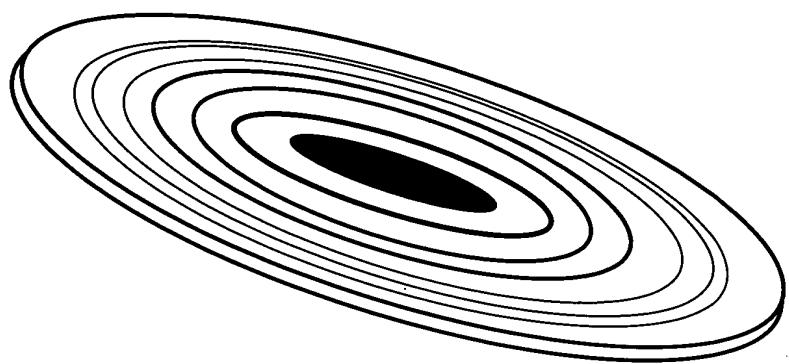


FIG.1



00000000 - 022100

FIG.2A

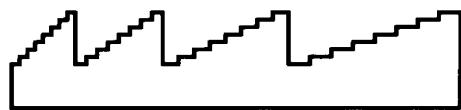


FIG.2B



FIG.3

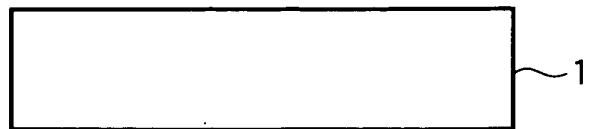
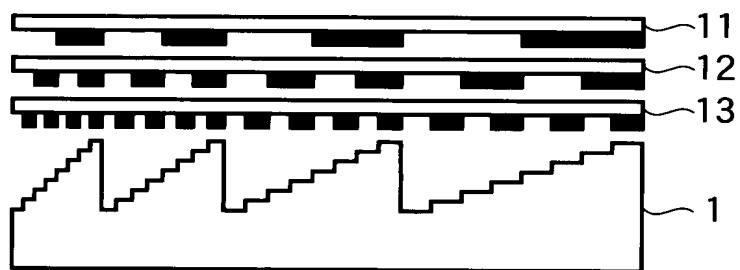


FIG.4



09040223 - 020402

FIG.5

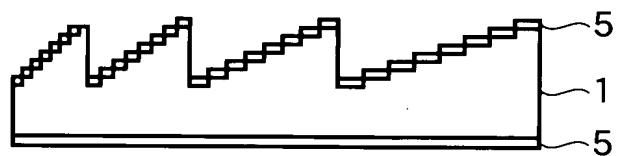


FIG.6

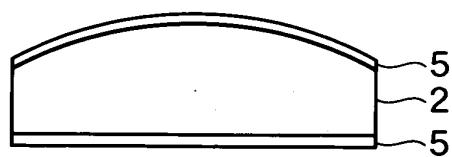


FIG.7

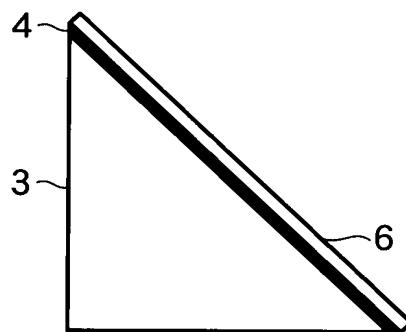


FIG.8

ILLUMINATION SYSTEM

MASK

PROJECTION SYSTEM

WAFER

The diagram illustrates a lithography system. On the left, a large brace groups the 'ILLUMINATION SYSTEM' (represented by a rectangle) and the 'PROJECTION SYSTEM' (represented by an irregular pentagon). To the right of the brace is a horizontal line representing a 'MASK'. Further to the right is another horizontal line representing a 'WAFER'.